

MAR 07 2003

Sheet 1 of 2

PTO-1449 (Modified) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT	ATTY. DOCKET NO. 207.008-US	SERIAL NUMBER 10/627,237
	APPLICANT(S) Lutz et al.	
	FILING DATE July 25, 2003	GROUP ART UNIT 2822

U.S. PATENT DOCUMENTS

EXAMINER INITIALS	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE
MP	4,849,071	7/1989	Evans et al.			
MP	4,945,769	8/1990	Sidner et al.			
MP	5,445,991	8/1995	Lee			
MP	5,470,797	11/1995	Mastrangelo			
MP	5,616,514	4/1997	Muchow et al.			
MP	6,521,508	2/2003	Cheong et al.			
MP	2004/0016989	1/2004	Ma et al.			
MP	6,621,134	9/2003	Zum			
MP	4,665,610	5/1987	Barth			
MP	4,766,666	8/1988	Sugiyama et al.			
MP	5,139,624	8/1992	Searson et al.			
MP	5,338,416	8/1994	Micak et al.			
MP	6,808,954	10/2004	Ma et al.			
MP	2004-0065932	4/2004	Reichenbach et al.			

FOREIGN PATENT DOCUMENTS

EXAMINER INITIALS	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION YES/NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

EXAMINER	DATE CONSIDERED 5/05
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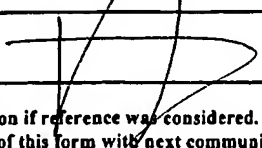
EXAMINER INITIALS	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE

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EXAMINER INITIALS	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION YES/NO	
MP	WO 01/46066	6/2001	PCT	—	—	—	—
MP	GB 2 198 611	6/1988	Great Britain	—	—	—	—
MP	WO 97/49475	12/1997	PCT	—	—	—	—
MP	EP 0 451 992	10/1991	European	—	—	—	—

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

MP	"Permeable Polysilicon Etch-Access Windows for Microshell Fabrication", Lebouitz K S et al., International Conference on Solid-State Sensors and Actuators and Eurosensors, 25 June 1995 (1996-06-25), pp. 224-227
MP	"Porous Polycrystalline Silicon: A New Material for MEMS", Anderson R C et al., Journal of Microelectromechanical Systems, March 1994, USA, vol. 3, no. 1, pp.10-18
MP	"Vacuum Encapsulation of Resonant Devices Using Permeable Polysilicon", Lebouitz et al., 1999 IEEE, pp.470-475
MP	"Laterally Grown Porous Polycrystalline Silicon: A New Material for Transducer Applications", Anderson et al., 1991 IEEE, pp.747-750

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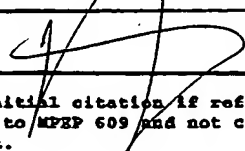
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EXAMINER INITIALS	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE
MP	5,578,250	11/1996	Diem et al.	—	—	—
MP	6,048,774	4/2000	Yamamoto et al.	—	—	—
MP	6,240,782	6/2001	Kato et al.	—	—	—

FOREIGN PATENT DOCUMENTS

EXAMINER INITIALS	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION Y/N/NO

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